## Characterization and Manipulation at Nanometer Scale Syllabus (2008)

Week 1 (2/19)	Overview
Week 2 (2/26)	STM: structure and working principles
Week 3 (3/04)	AFM: structure and working principles
Week 4 (3/11)	SPM: structure and working principles
Week 5 (3/18)	TEM: structure and working principles
Week 6 (3/25)	TEM: operations and examples
Week 7 (4/01)	X-ray and other microscopies
Week 8 (4/08)	Midterm Written Exam (50%)
Week 9 (4/15)	Spectroscopy: optical, electronic, vibrational
Week10 (4/22)	Lithography: optical, e-beam
Week11 (4/29)	Atom manipulation
Week12 (5/06)	Papers study
Week13 (5/13)	Papers study
Week14 (5/20)	Papers study
Week15 (5/27)	Papers study
Week16 (6/03)	Papers study
Week17 (6/10)	Presentation and responses (50%)



#### Nanoscale measurements

#### Jason Chang

Institute of Physics, Academia Sinica jasonc@phys.sinica.edu.tw

http://www.phys.sinica.edu.tw/TIGP-NANO/Course/2008\_Spring.htm

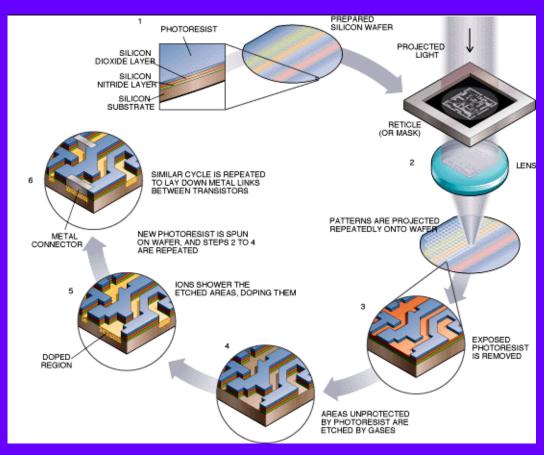
http://www.phys.sinica.edu.tw/~nano/



#### Outline

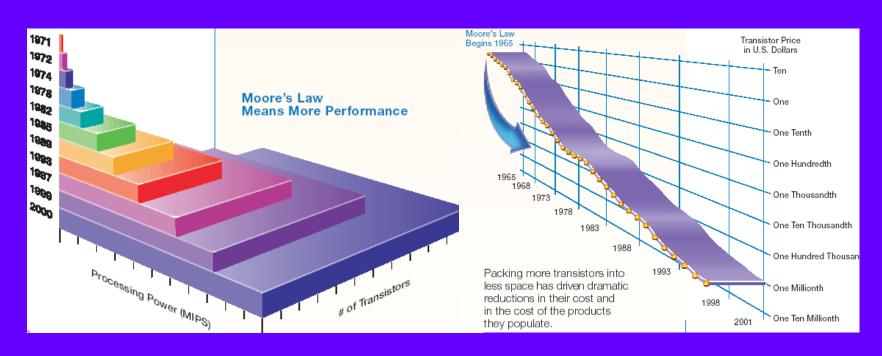
- A. Introduction
- **B.** Operational Principles:
  - a.Electron b.X-ray c.Scanning Probe
- C. From measuring to sensing
- D. From measuring to manipulating
- E. From measuring to fabricating
- F. Considerations for making nanoscale tools
- G. Future development of nanoscale measurements
- H. Conclusions

# Optical lithography and planar fabrication of VLIC





#### Numbers of transistors in an IC

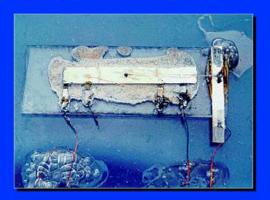


Intel Corp.

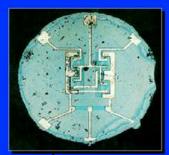


### Evolution of IC industry

#### Kilby's First IC, 1958



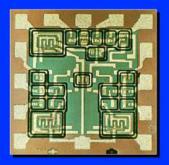
#### The First Planar Integrated Circuit, 1961



Jean Hoerni

#### 1965

This DTL triple-gate device was the first radiation hardened product made with dielectric isolation and thin-film resistors.

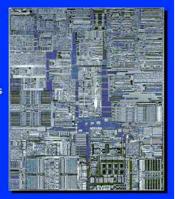


#### **Modern IC**

#### Pentium® III Processor

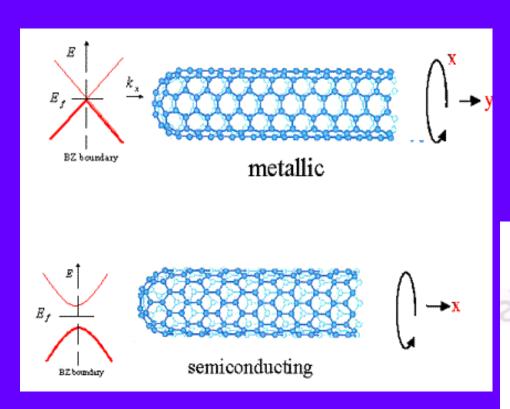
Transistors: 9,503,153

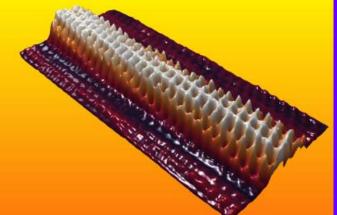
Die Size: 408.9 mils x 484.8 mils Area: 127.9 mm²

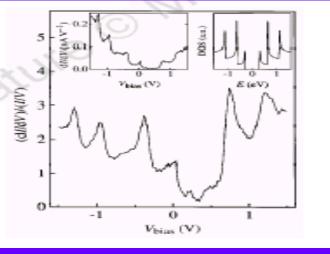




# Electronic properties of a carbon nanotube

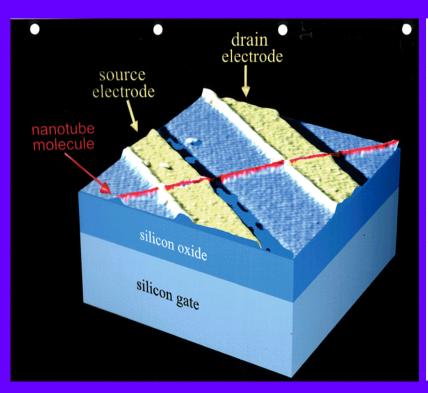


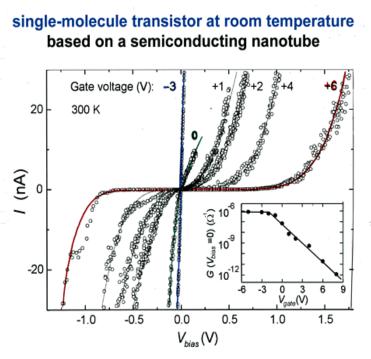






## Single-walled CNT transistor





S.J. Tans et al., Nature 393, 49 (1998).



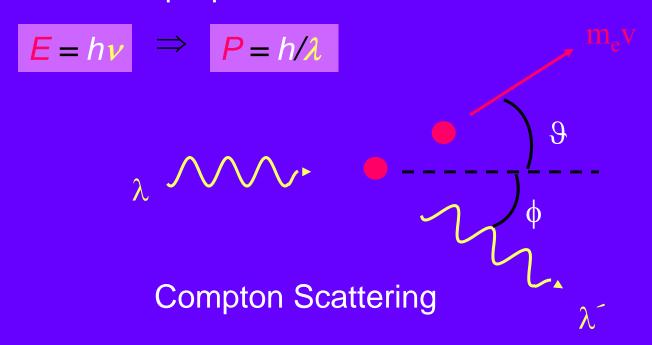
Nanoscience is the study of phenomena and manipulation of materials at atomic, molecular and macromolecular scales, where properties differ significantly from those at a larger scale.

Nanotechnologies are the design, characterization, production and application of structures, devices and systems by controlling shape and size at nanometer scale.



#### Photon as a particle

#### Einstein's proposal:





#### Electron as a wave

#### de Broglie's proposal:

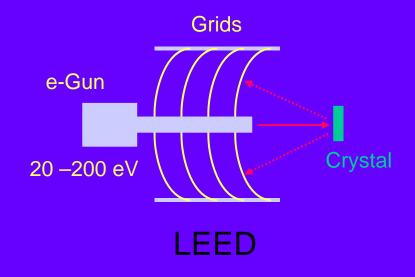
$$\lambda = h/P \implies \nu = h/E$$

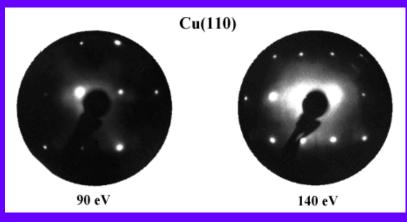


$$v = h/E$$

#### For electrons:

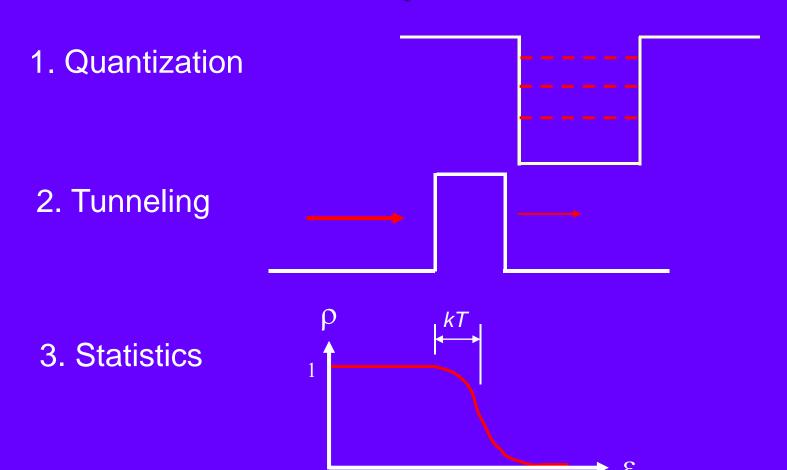
$$\lambda (nm) = 1.22/E^{1/2}(eV)$$





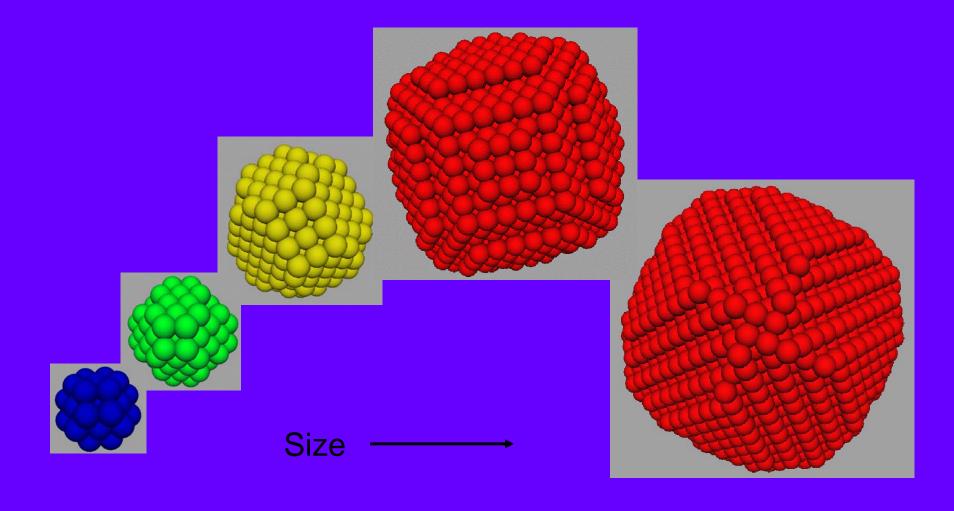


#### Fundamentals of Quantum Mechanics



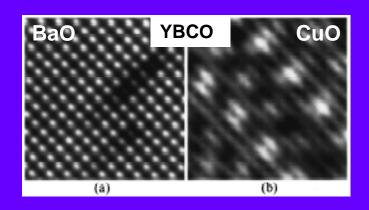


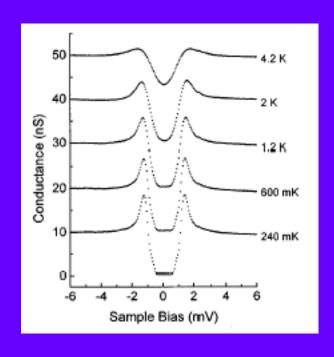
## Size effect





### Measurement of electronic states





S. H. Pan et al., Rev. Sci. Instru. 40, 1459 (1999).

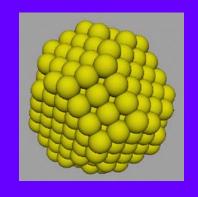


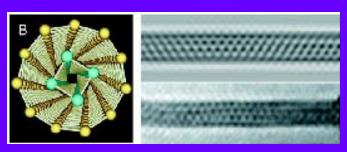
#### Properties of a nanostructure

#### Microscopic

Size
Structure
Shape
Symmetry
Domains

Defects





#### **Analytical**

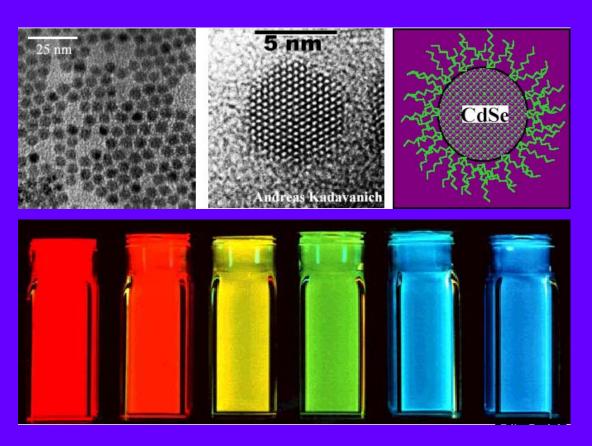
Composition
Stoichiometry
Electronic
Magnetic
Thermal
Mechanical

÷

photons, electron, ion, neutron, proximal nanoobjects ...



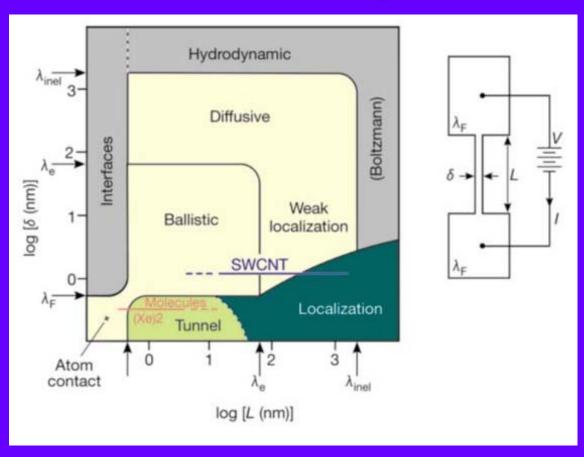
## Semiconducting quantum dots



(Reproduced from Quantum Dot Co.)



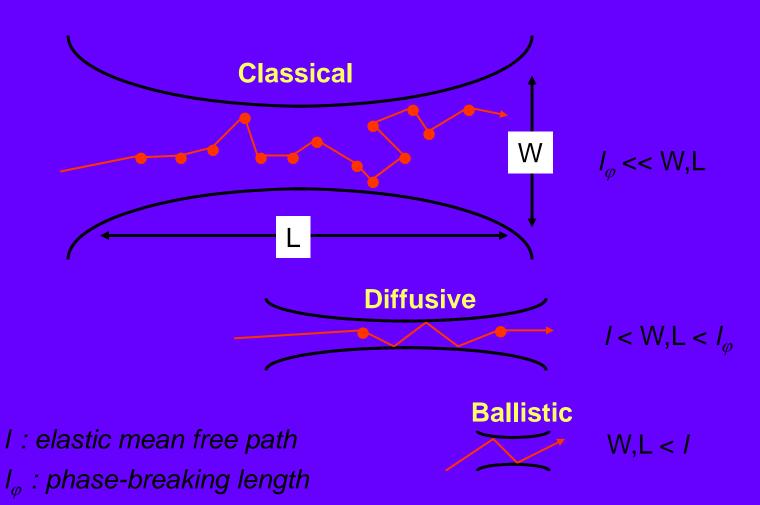
### Critical lengths



C. Joachim et al., Nature 408, 541 (2000).



## Characteristics of electron transport





## Minituralization of length scale

Macro --- Nano

continual

scalable

evolutionary

classical

discrete

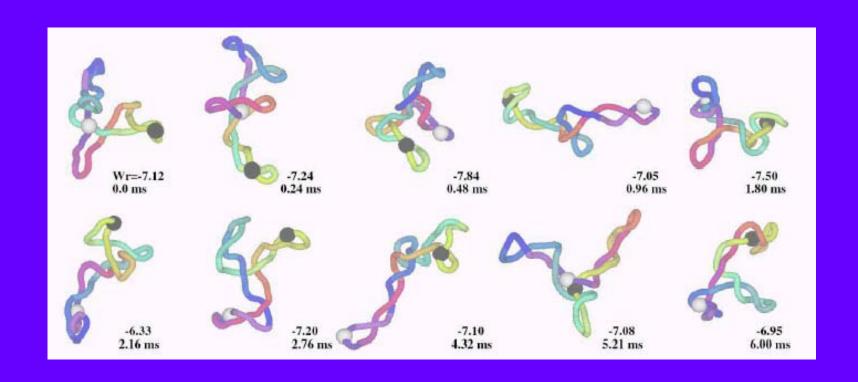
nonscalable

revolutionary

quantum mechanical

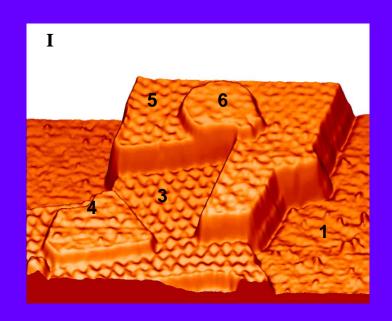


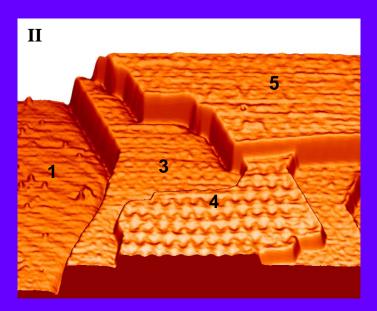
## Simulation of DNA dynamics





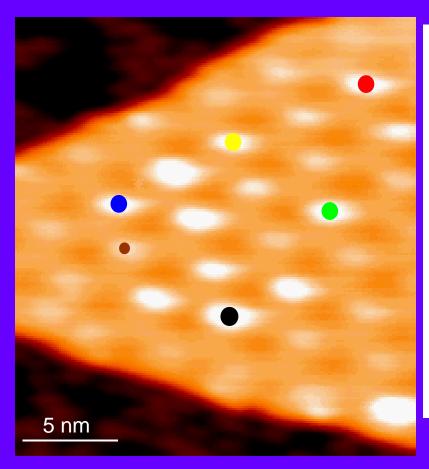
## Alternating and complementary contrast

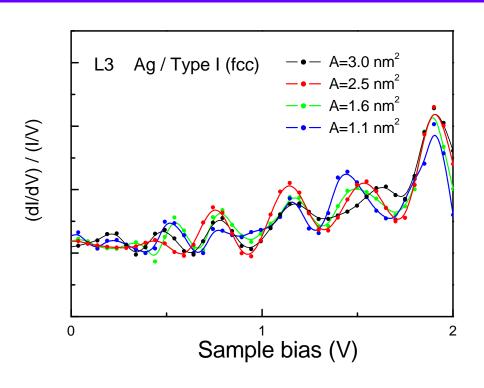




W.B. Jian et al. PRL 90, 196603 (2003)

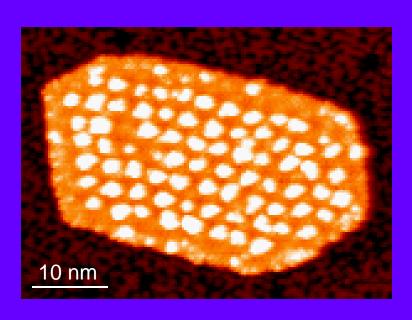
#### Size-dependent I/V spectra by STS

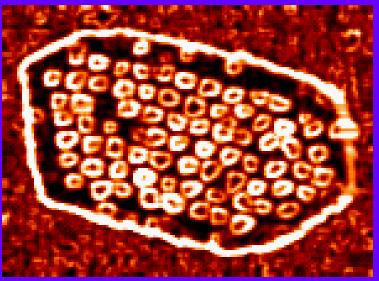






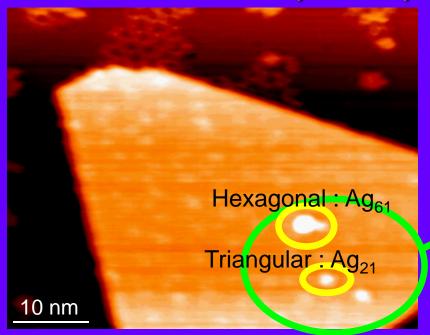
## Shapes of Ag nanopucks

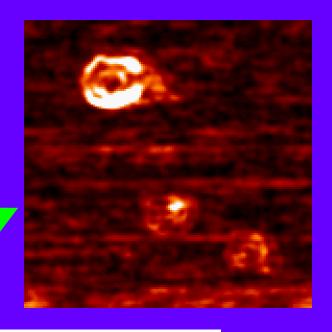


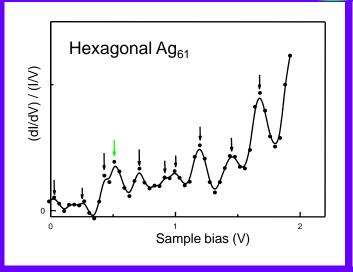


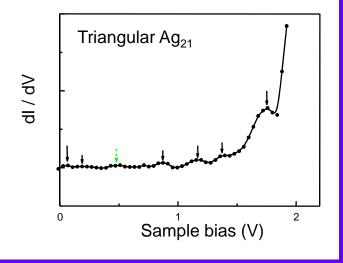


### Size- and shape-dependent I/V spectra











### Characterization of single nanostructure

Specs

Demands • Small size high brightness

small probe

• Weak signal high sensitivity

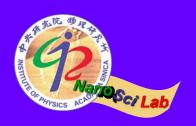
low interference

 High reactivity controlled environment

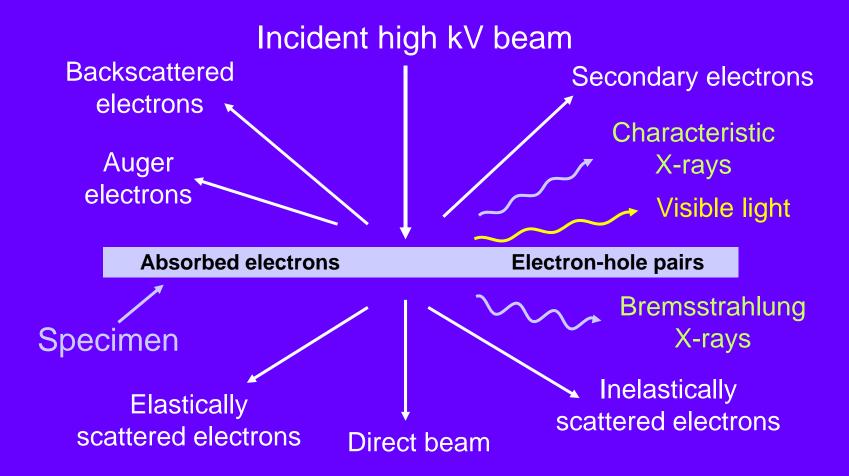
low temperature

• Flexible high speed

in situ measurement functionality

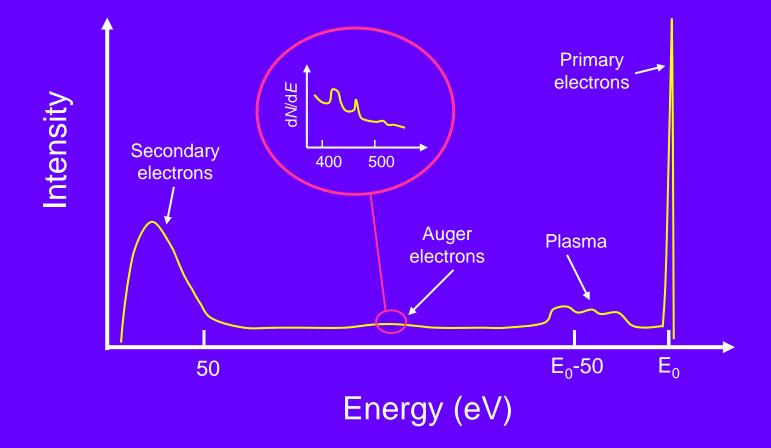


## Interaction between e-beam and sample





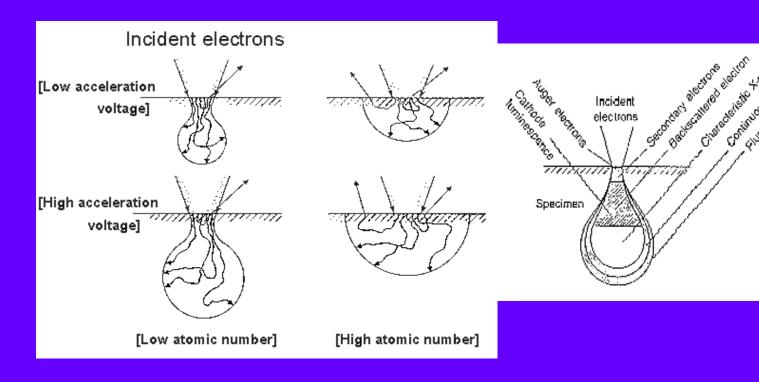
#### Energy distribution after interaction



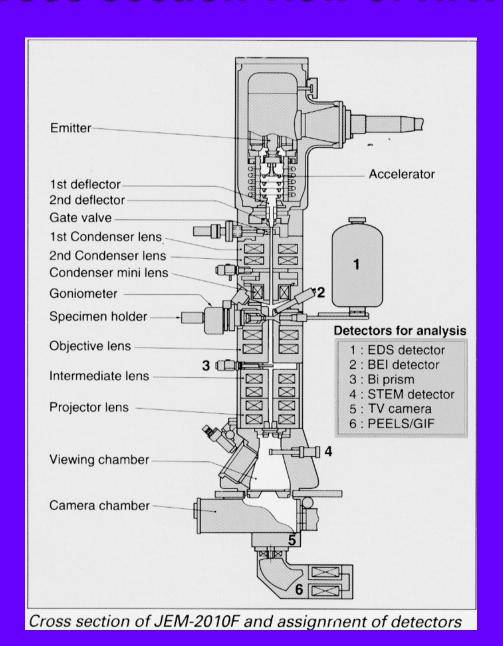


## Penetration power of energetic e beam

Characteristic X-tops Continuous Trans

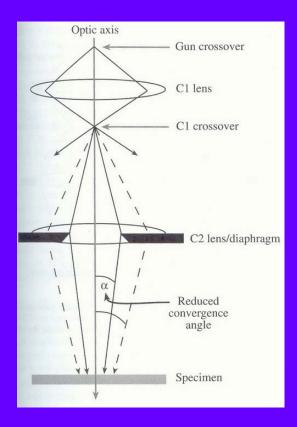


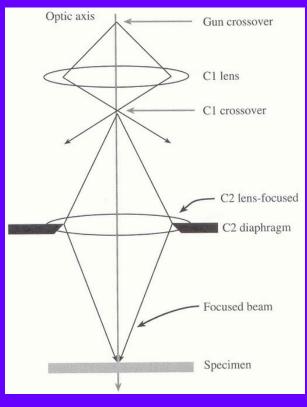
#### **Cross section view of HRTEM**





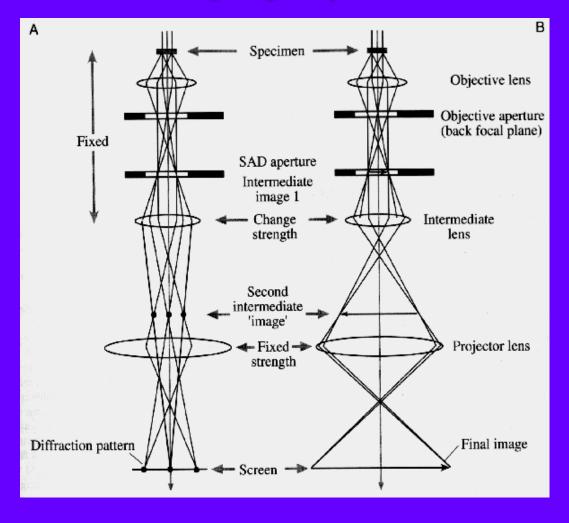
## E-beam source of TEM





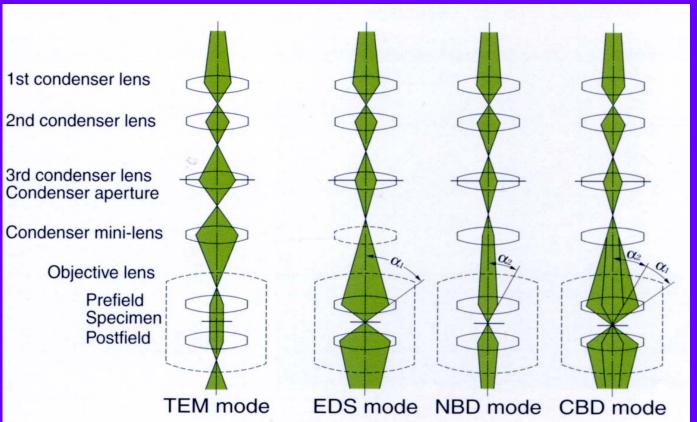


## Imaging system

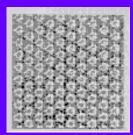


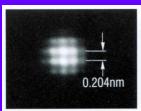


#### Quick Beam Select System









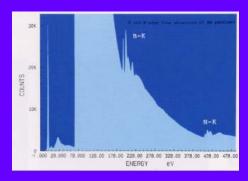




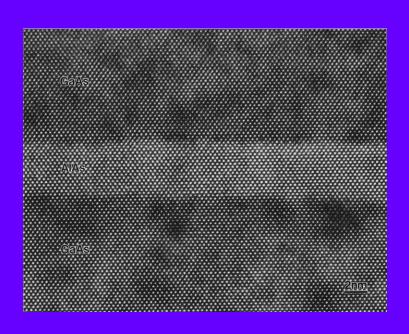
#### **Information from TEM**



#### **EDS**



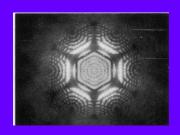
**EELS or GIF** 



Lattice image GaAs/AlAs



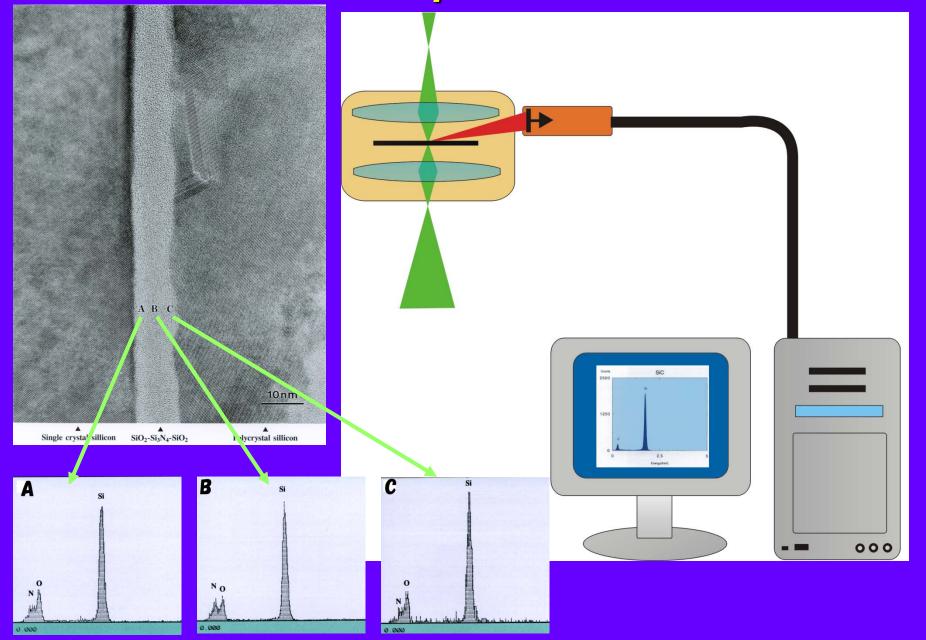
**Electron Diffraction** 



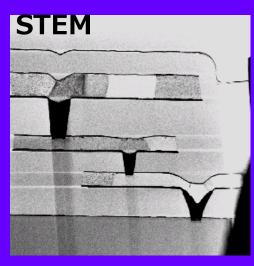
**CBED** 

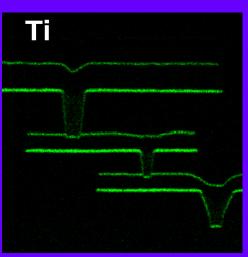
STEM+BF, HAADF → Mapping and Z-contrast image

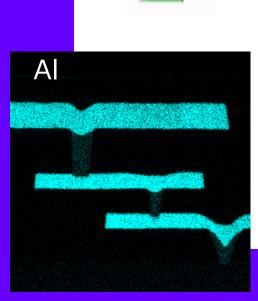
#### EDS with spatial resolution

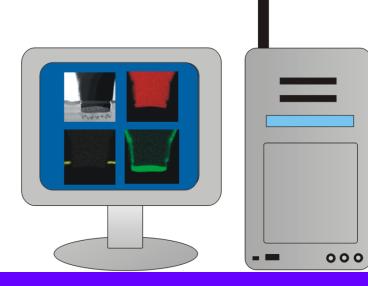


#### EDS mapping

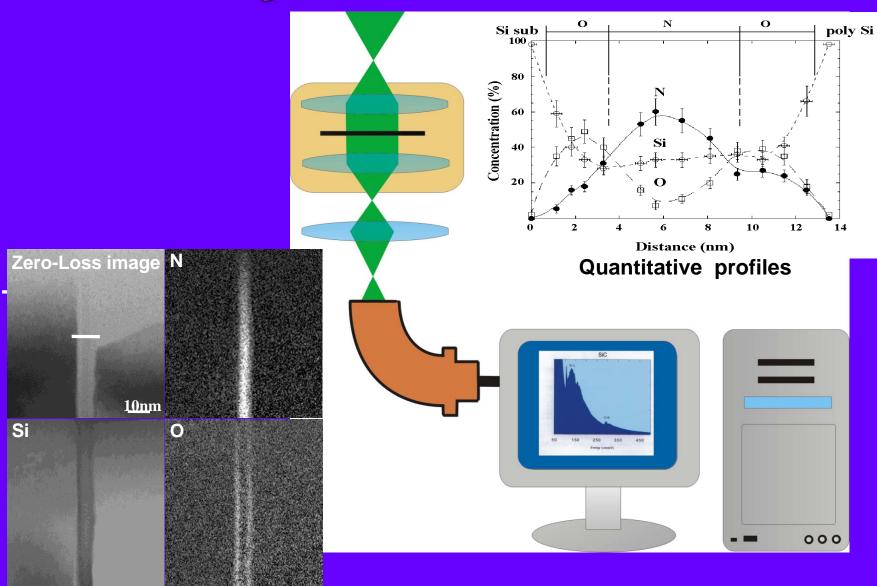




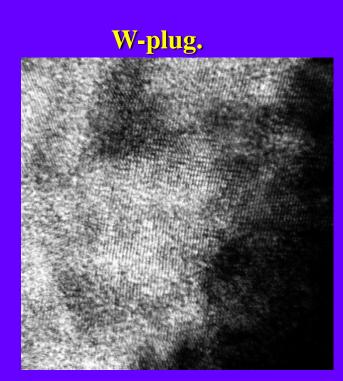


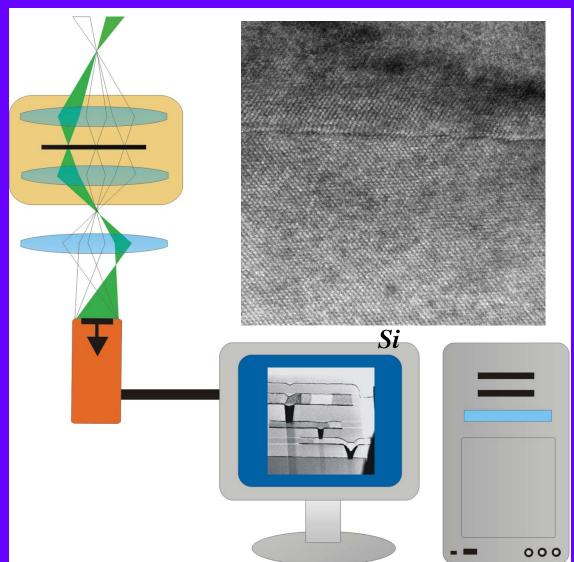


#### High resolution EELS

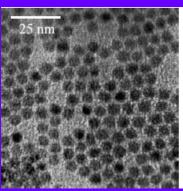


#### High resolution STEM image

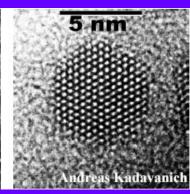


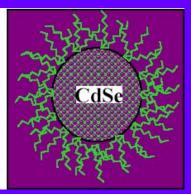


## Semiconducting quantum dots and carbon nanotubes

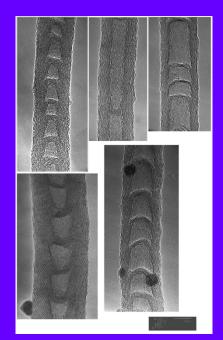


Nario Sci Lab

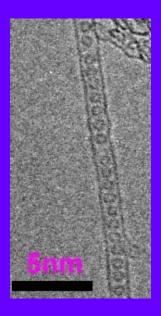




(Reproduced from Quantum Dot Co.)



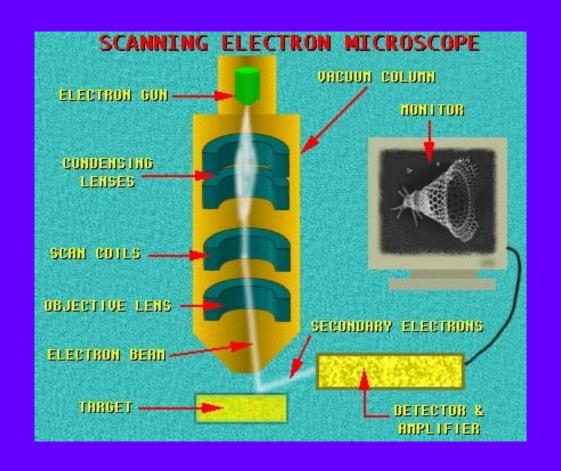
**Multiwall CNT** 



**Peapod CNT** 



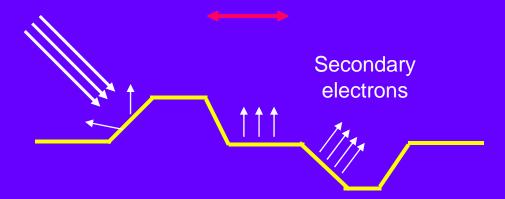
## Scanning electron microscopy (SEM)

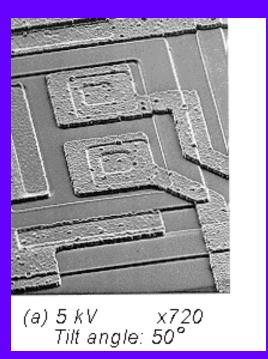




#### **SEM contrast**

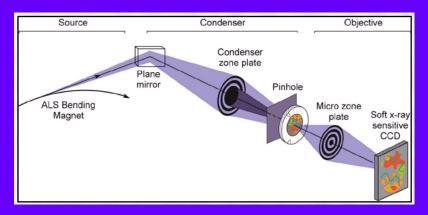
#### Scanning e beam

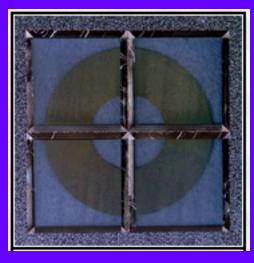


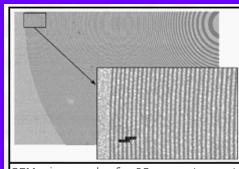




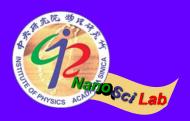
## X-Ray Microscopy





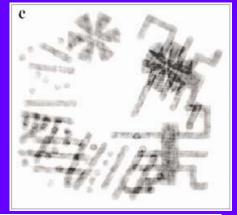


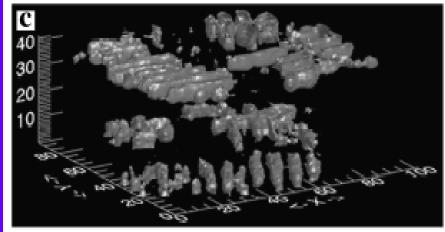
SEM micrograph of a 25-nm-outermost zone width micro zone plate. Diameter = 63mm, 628 zones, gold plated.



## 3D X-Ray Image



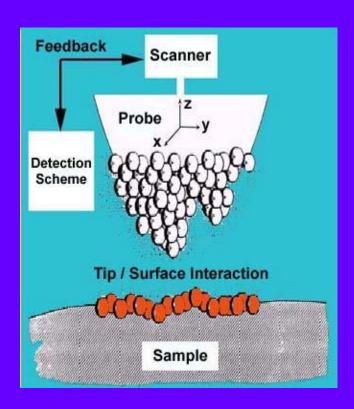




J. Miao et al., PRL 89, 088303 (2002).



## Historical development of SPMs



#### **Scanning Tunneling Microscopy (STM)**

--- G. Binnig, H. Rohrer et al, (1982)

#### **Near-Field Scanning Optical Microscopy (NSOM)**

--- D. W. Pohl (1982)

#### **Atomic Force Microscopy (AFM)**

--- G. Binnig, C. F. Quate, C. Gerber (1986)

#### Scanning Thermal Microscopy (SThM)

--- C. C. Williams, H. Wickramasinghe (1986))

#### **Magnetic Force Microscopy (MFM)**

--- Y. Martin, H. K. Wickramasinghe (1987)

#### **Friction Force Microscopy (FFM or LFM)**

--- C. M. Mate et al (1987)

#### **Electrostatic Force Microscopy (EFM)**

--- Y. Martin, D. W. Abraham et al (1988)

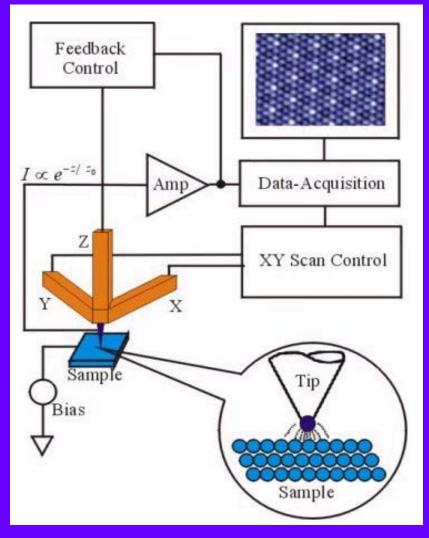
#### **Scanning Capacitance Microscopy (SCM)**

--- C. C. Williams, J. Slinkman et al (1989)

#### **Force Modulation Microscopy (FMM)**

--- P. Maivald et al (1991)

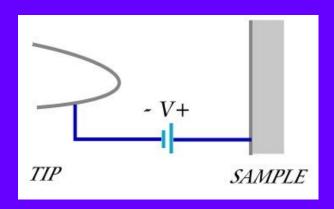


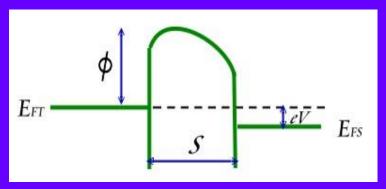


## Scanning Tunneling Microscopy



#### Theory of STM

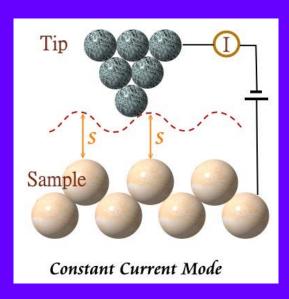


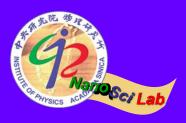


From one-dimensional tunneling problem tunneling current (eV<<  $\phi$  )

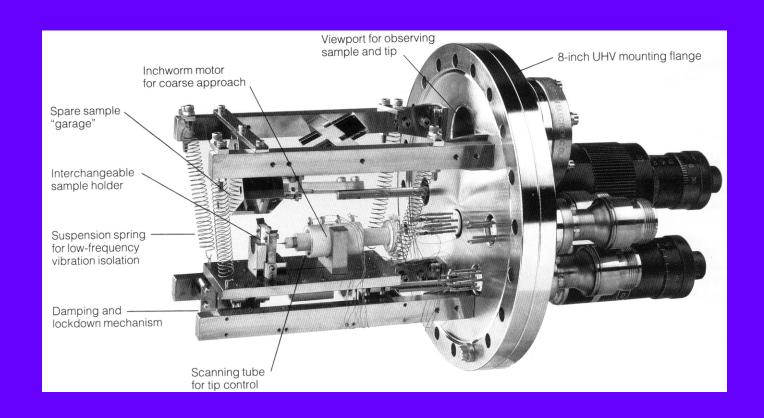
$$I \propto \frac{V}{S} \exp\left(-A\phi^{\frac{1}{2}}S\right)$$

$$A = 1.025 (eV)^{-0.5} \text{ Å}^{-1}$$



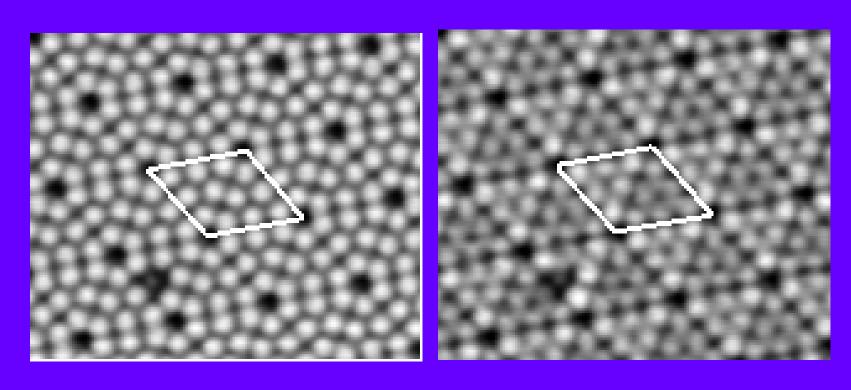


#### **UHV STM**





### STM Images of Si(111)-(7×7)



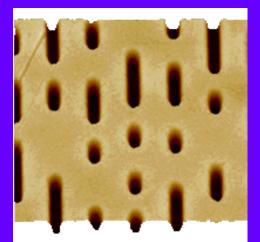
**Empty-state image** 

Filled-state image

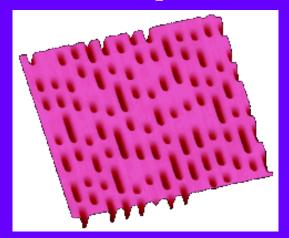


#### AFM images

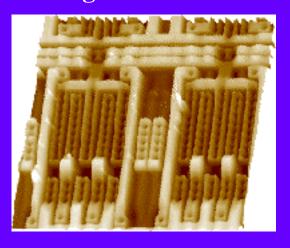
**CD** pits



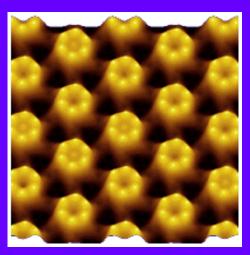
**DVD** pits



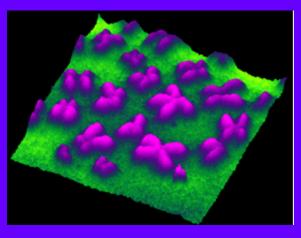
**Integrated Circuit** 



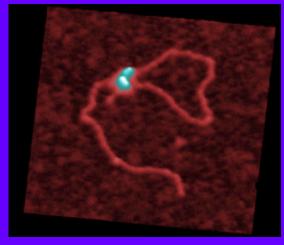
Bacteria



Chromosomes



**DNA** 

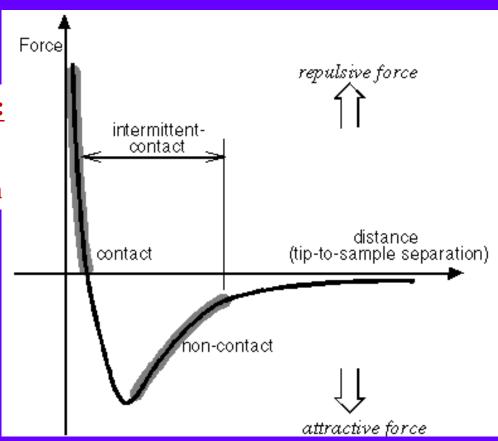




#### Interaction between the probe and sample



- 1) Bonding
- 2) Repulsion



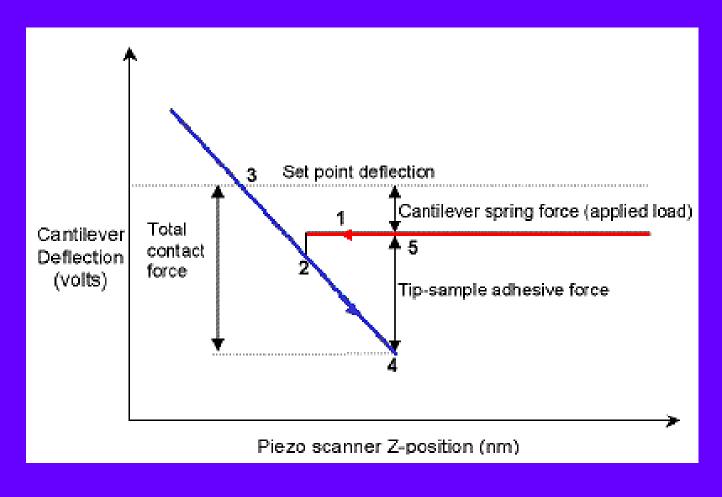
#### **Long-range:**

- 1) Van der Waal
- 2) Capillary
- 3) Magnetic
- 4) Electrostatic

Lennard-Jones potential  $\phi(r) = -A/r^6 + B/r^{12}$ 

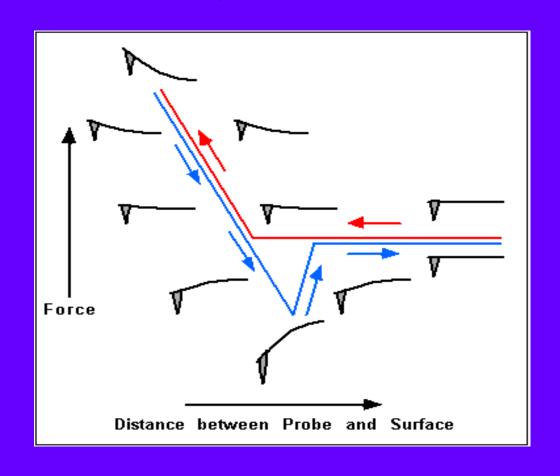


### Deflection of Cantilever vs Piezo displacement



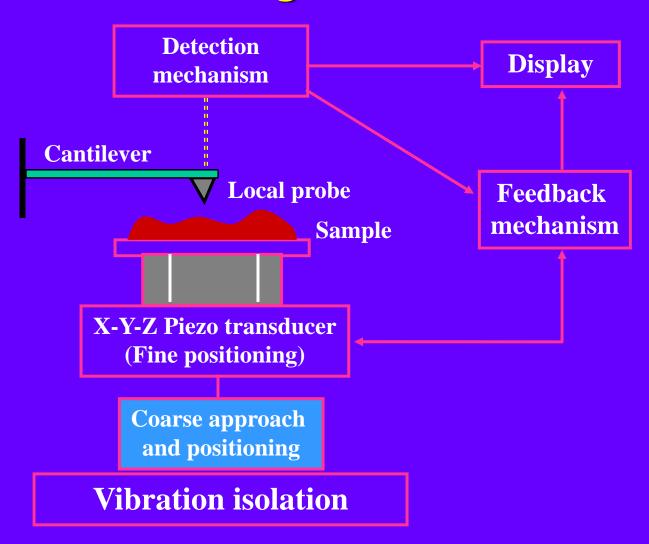


## Reaction of probe to the force



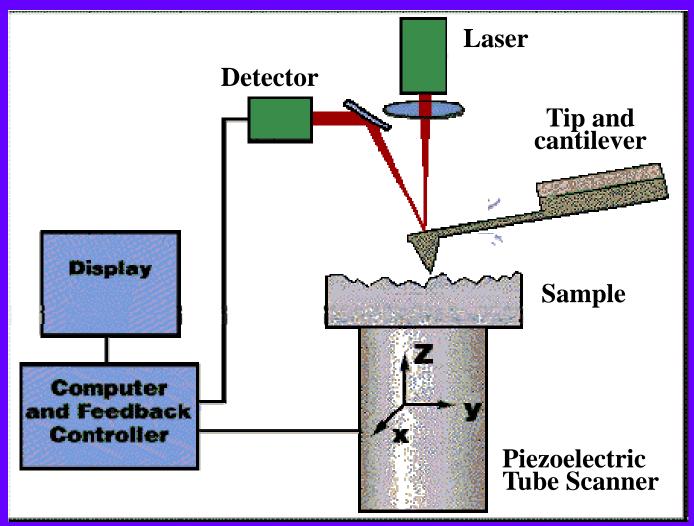


#### Basic configuration of AFM



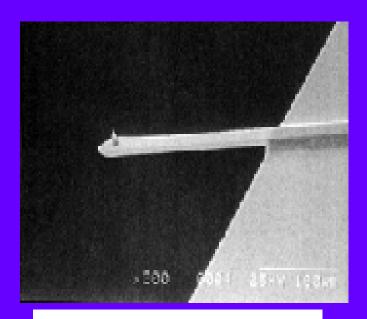


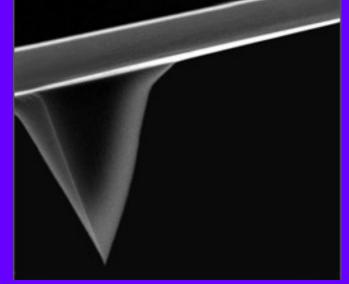
## Core components of an AFM



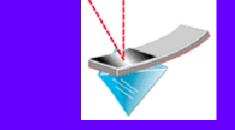


### Probes for the tapping mode





Typical Tip Dimension:  $150\mu m \times 30\mu m \times 3\mu m$   $f_r \sim 100 \text{ kHz}$  Materials: Si





## Comparisons among various microscopies

	光學顯微術 (OM)	掃描電子顯微術 (SEM)	穿透電子顯微術 (TEM)	掃描探針顯微術 (SPM)
lateral	300nm	1nm	0.1nm	0.1nm
vertical	20nm	10nm		0.01nm
Imaging area	1 mm	1 mm	0.1mm	0.1mm
Imaging environ	none	vacuum	vacuum	none
Sample prep	no	yes	yes	no
Elemental anal	yes	yes	yes	no

## Molecular Scale Nanomechanics Driving Force in Bio-systems

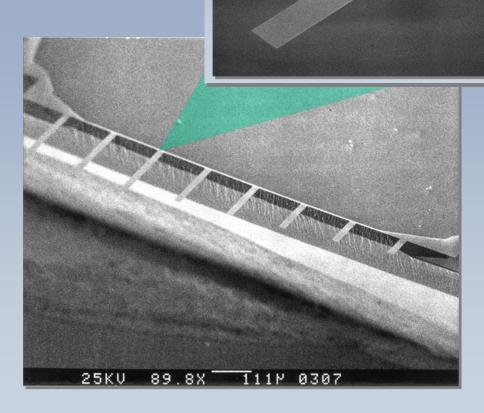
At the fundamental level, all interactions in biology and chemistry are mechanical in nature

# **Mechanical Sensing in Nature** Hair bundle: frog's inner ear

Micro and Nano cantilever arrays 
Emulating nature

- Ideal displacement sensor
  - Sub nm sensitivity
- Displacement ~ force
- Surface stress, temperature
- Mass loading

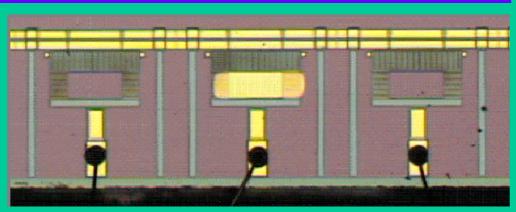
Sesitivity:
Function of dimensions
Selectivity:
Function of coatings

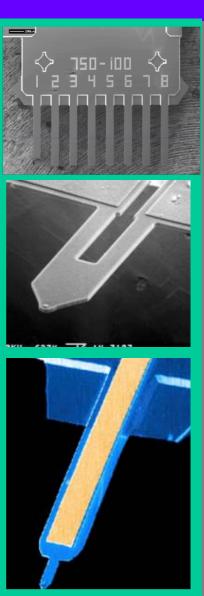


Mass production

## Microcantilevers: Getting the signal out

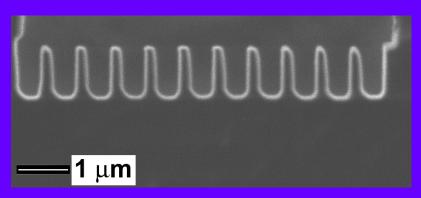
- Optical
- Piezoresistivity
- Piezoelectricity
- Capacitance

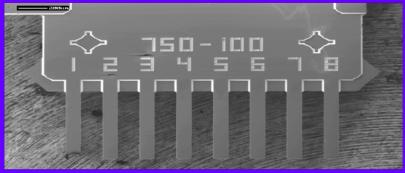




#### Microcantilevers To Nanocantilevers

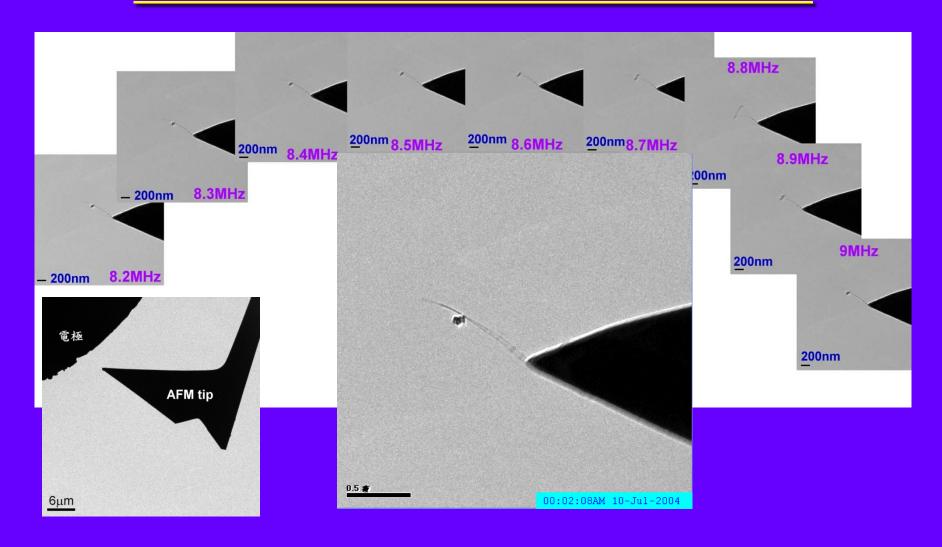
- Increased Sensitivity
- High Resonance Frequency
- Small Spring Constants
- Single Molecule Detection
- Challenges:
  - Signal Transduction
  - Mass production





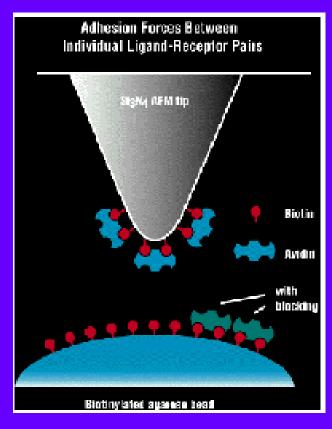
(Craig Prater, DI)

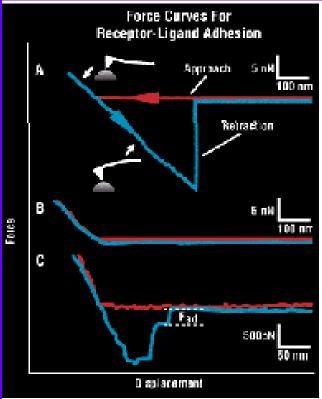
#### Nanoelectromechanical oscillator





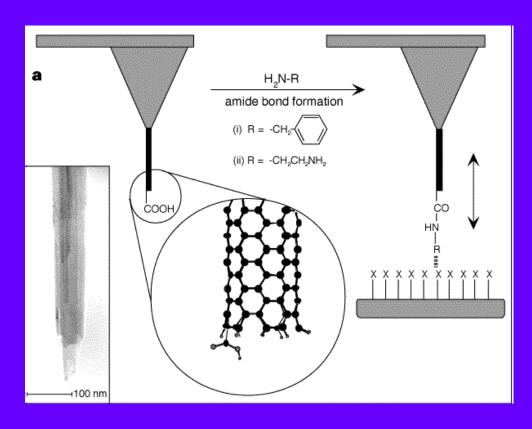
#### Molecular sensing



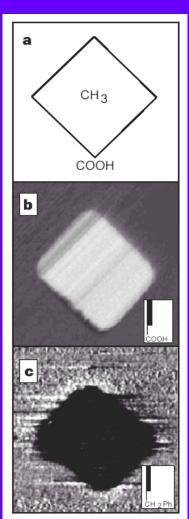




### Chemical nanoprobe



S. S. Wong et al., Nature 394, 52 (1998).

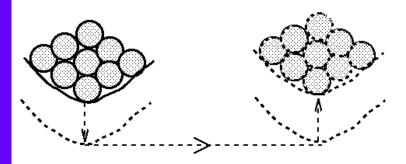


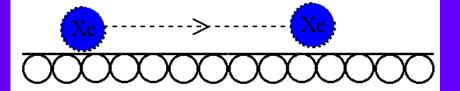


#### Manipulation method

#### Positioning Atoms with an STM

D.M. Eigler & E.K. Schweizer Nature 344 524 (1990)



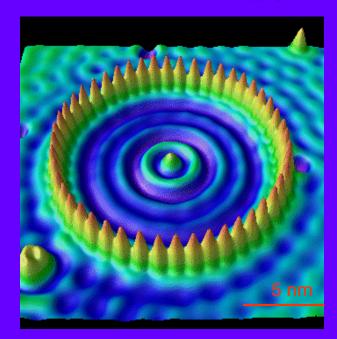


The STM tip is brought down near the atom, until the attraction is enough to hold it as the atom is dragged across the surface to a new position.



## Ultimate goal of nanotechnology

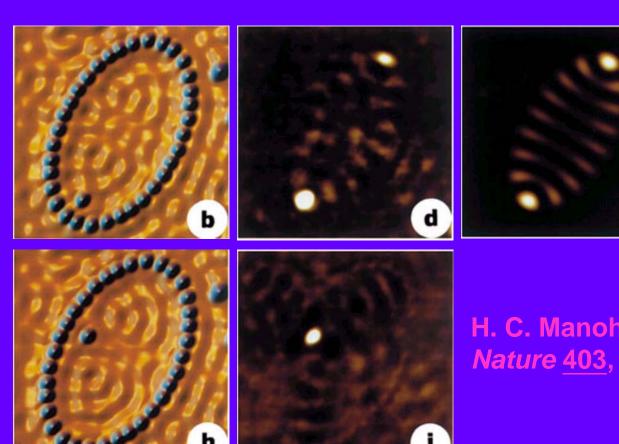




M.F. Crommie *et al., Science* 262, 218 (1993).



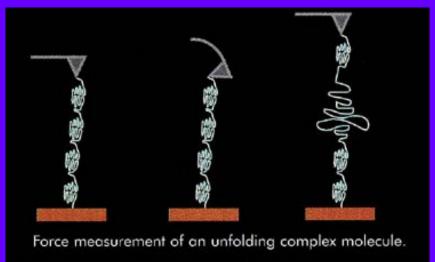
### Quantum Mirage

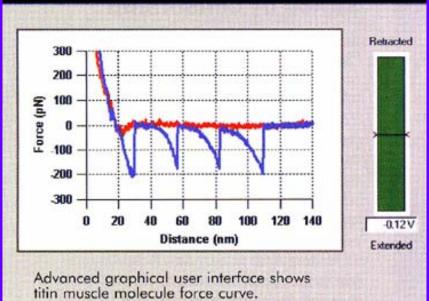


H. C. Manoharan et al., *Nature* 403, 512 (2000).



#### Molecular unfolding



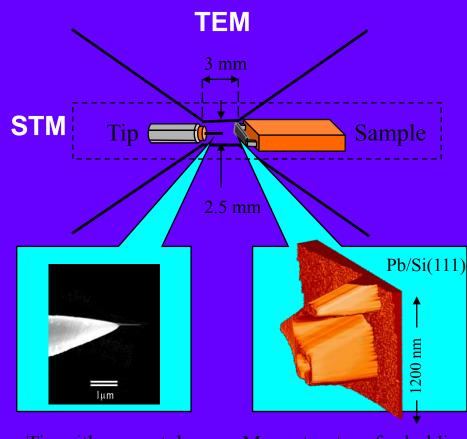




#### UHV HRTEM/STM



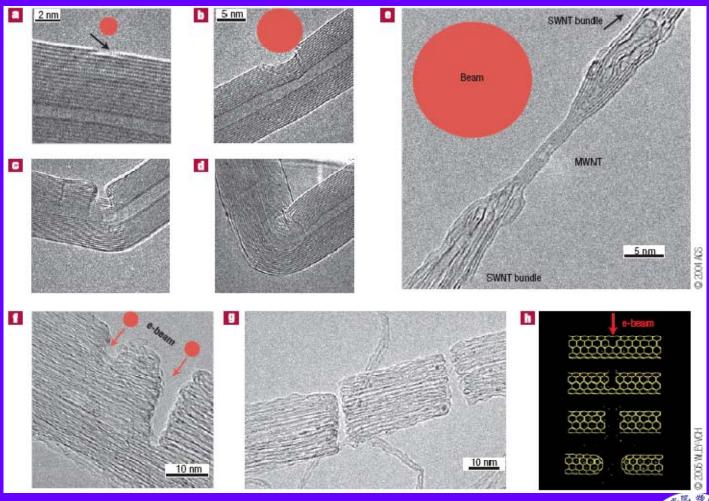




Tip with a nanotube Mes

Mesa structure for holding the nano-object

#### Engineering CNT with energetic e-beam

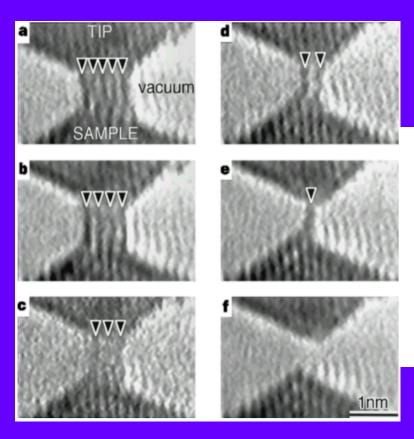


A.V. Krasheninnikov and F. Banhart *Nature Materials* **6**, 723 (2007)

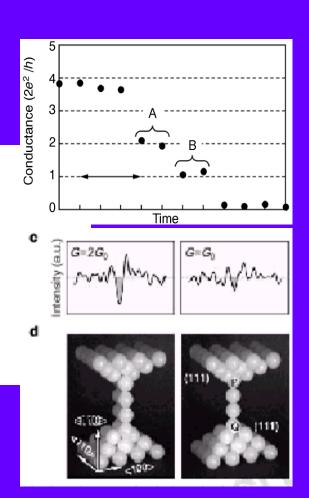




#### Point contact of Au wire

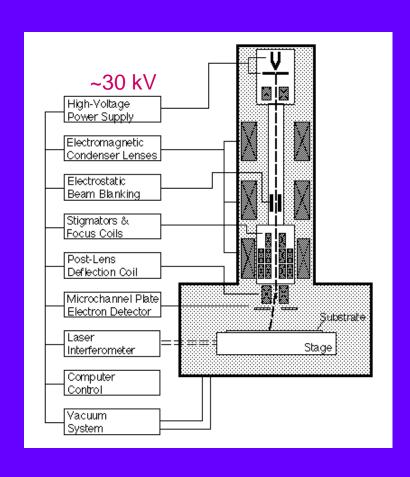


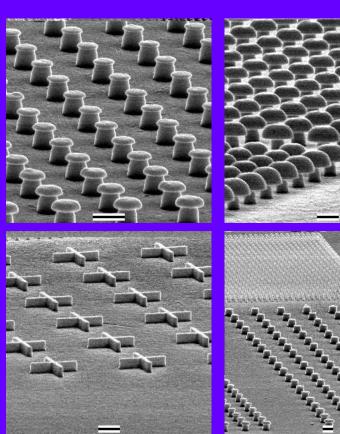
H. Ohnishi *et al.* Nature 395, 780 (1998).



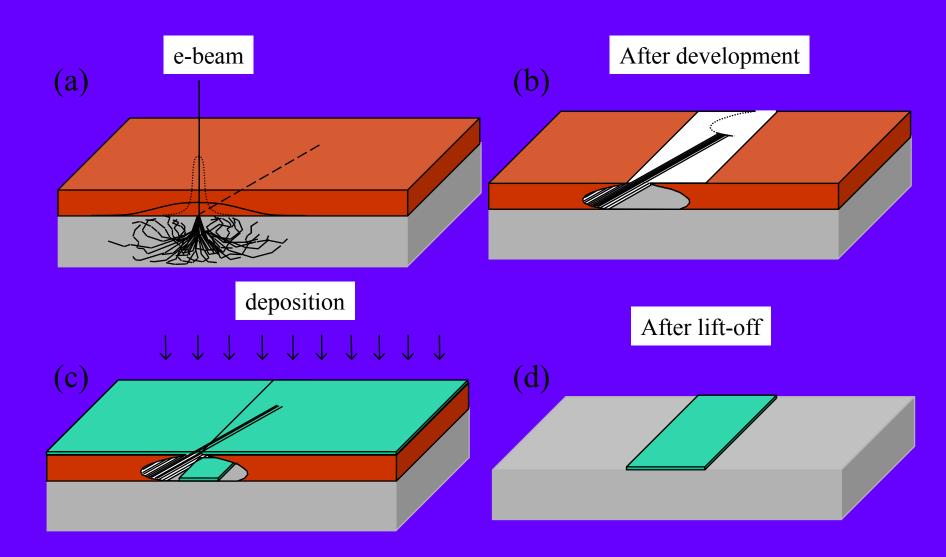


### Periodic nanostructures by e-beam lithography



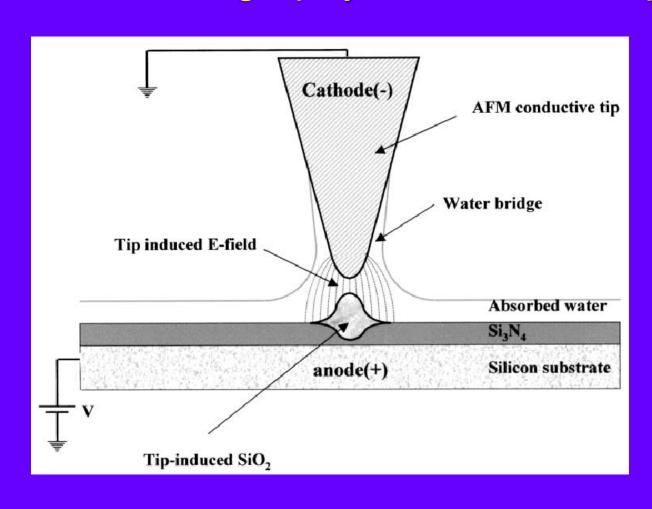


## Procedures of e-beam lithography



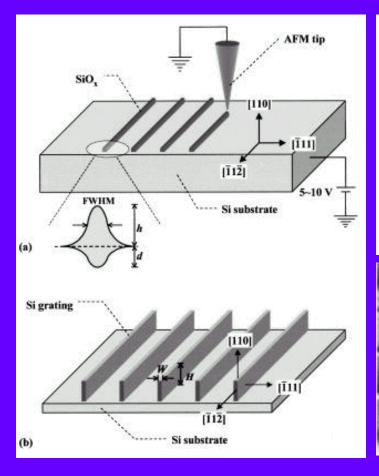


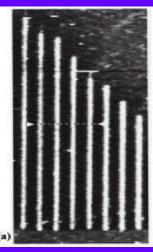
#### Nano-Lithography with an AFM tip

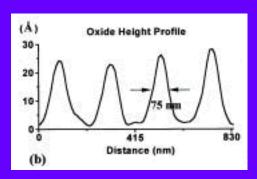




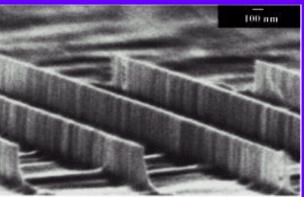
## Electrical Lithography





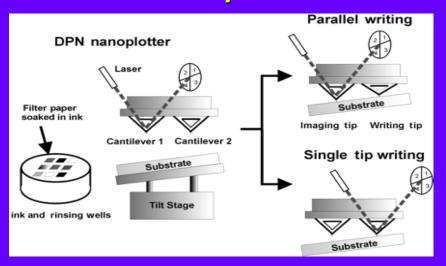


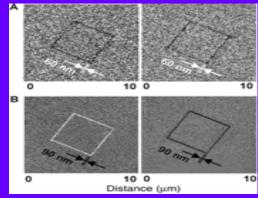
F.S.-S. Chien *et al*. APL <u>75</u>, 2429 (1999)



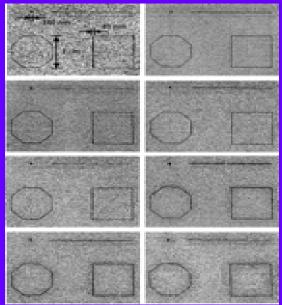


## Nanoplotter



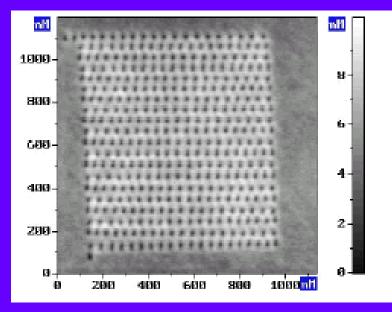


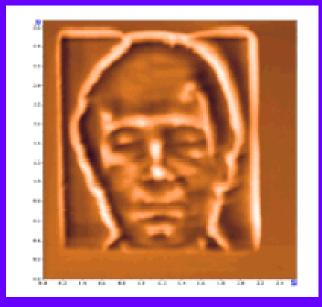
C.A. Mirkin *et al.*Science <u>288</u>, 1808 (2000)





### Nanolithography of Tapping-Mode AFM





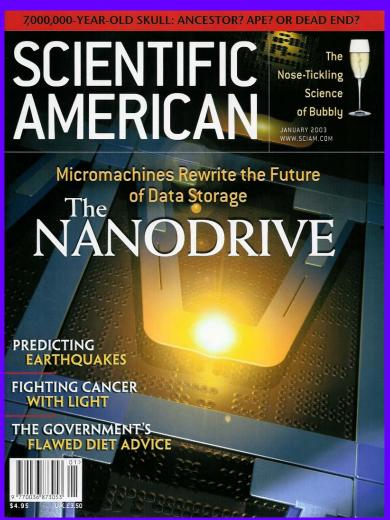
 $(1.2 \mu m \times 1.2 \mu m)$ 

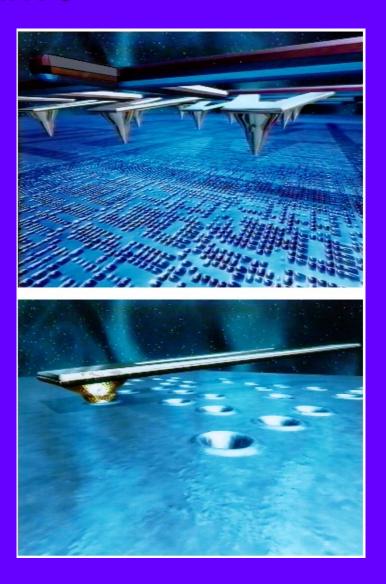
 $(2.5\mu m \times 2.5\mu m)$ 

Image of polycarbonate film on silicon surface



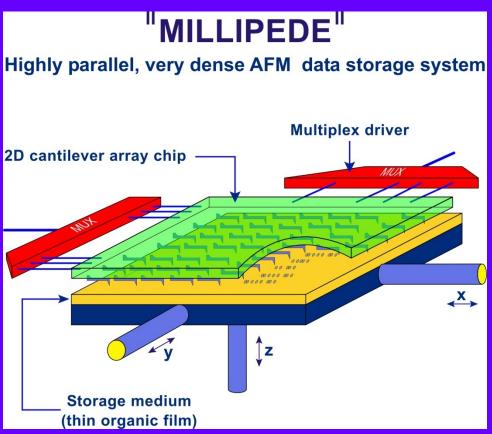
#### Nanodrive







### Millipede

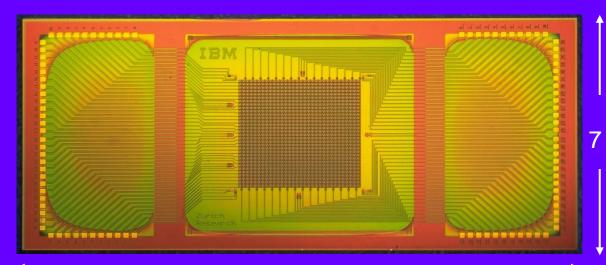


The Millipede concept: for operation of the device, the storage medium - a thin film of organic material (yellow) deposited on a silicon "table" - is brought into contact with the array of silicon tips (green) and moved in x- and y-direction for reading and writing. Multiplex drivers (red) allow addressing of each tip individually.

**IBM-Zurich** 

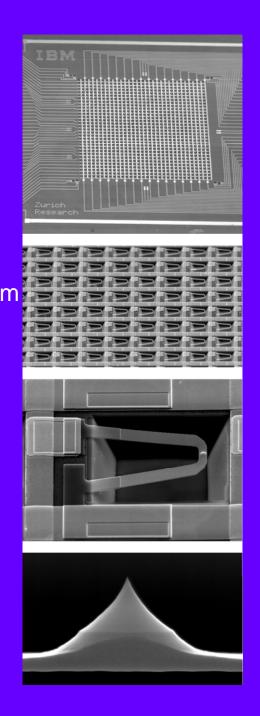


#### Cantilever array



14 mm

Millipede cantilevers and tips: electron microscope views of the 3 mm by 3 mm cantilever array (top), of an array section of 64 cantilevers (upper center), an individual cantilever (lower center), and an individual tip (bottom) positioned at the free end of the cantilever which is 70 micrometers (thousands of a millimeter) long, 10 micrometers wide, and 0.5 micrometers thick. The tip is less than 2 micrometers high and the radius at its apex smaller than 20 nanometers (millionths of a millimeter).





# Considerations for making nanoscale tools

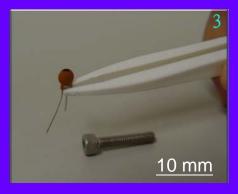
- 1. Size compatibility
- 2. Force compatibility
- 3. Mechanical Properties
- 4. Chemical Properties
- 5. Precision movement
- 6. Integratible coarse movement
- 7. Environment interferences

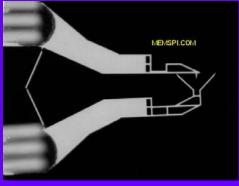


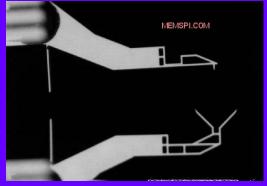
# Maneuvering tools

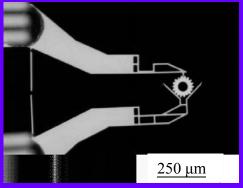






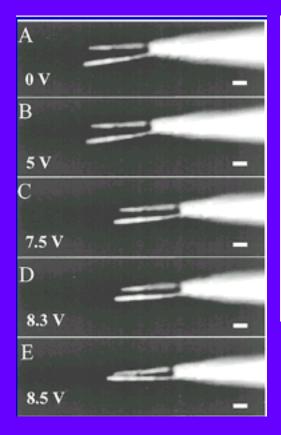


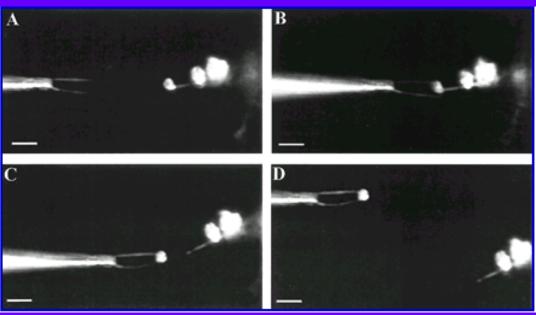






## Operation of nano tweezers

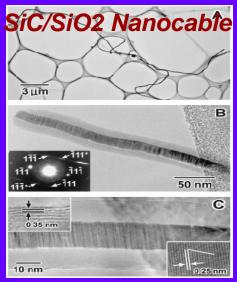




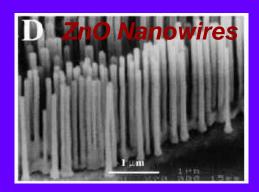
P. Kim and C.M. Lieber, *Science* 286, 2148 (1999).



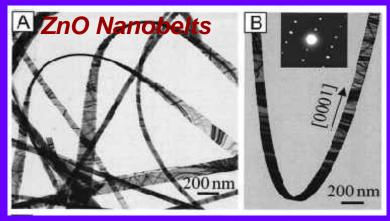
#### Nano wires and belts



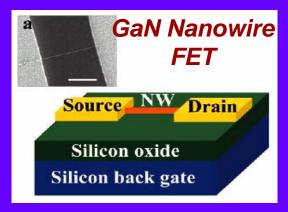
Science 281, 973 (1998)



Science 292, 1897 (2001)



Science 291, 1947 (2001)



Nano Lett. 2, 101 (2002)

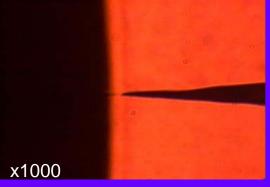


# Precision stepper





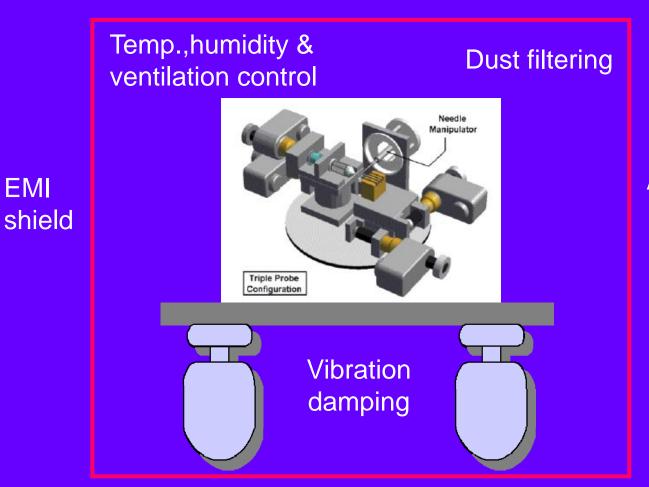




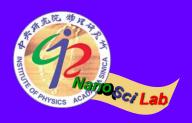


**EMI** 

## Considerations for environmental factors



Acoustic isolation



## Goals for next 5-10 years

- Instruments for analysis of supramolecules, biomolecules, and polymers.
- 3-D structure determination.
- Nanostructure chemical identification.
- In situ functional measurements.
- Functional parallel probe arrays.
- Standardization and metrology.
- New nano-manipulators.



#### References

- Scanning Tunneling Microscopy II, eds. R. Wiesendanger and H.-J. Guntherodt (Springer-Verlag, Berlin, 1992).
- 2. M. Stark and R. Guckenberger, Rev. Sci. Instru. 70, 3614 (1999).

#### Related links:

http://www.di.com/

http://www.topometric.com/



## 奈米國家型科技計畫核心設施中心

- •中央研究院
- •台灣大學
- •清華及交通聯合中心
- •中區核心設施中心
- •南區核心設施中心
- 東區核心設施中心